TRANSFER DEVICE AND EXHAUST METHOD

ABSTRACT

A transfer device for loading and unloading substrates to and from a processing apparatus configured to process the substrates includes a main body including a transfer space in which a transfer robot configured to transfer the substrates is provided. The main body further includes a housing constituting the transfer space, the housing including a wall configured to form a front surface to which a load port configured to support a container for accommodating the substrates is connected, a rear surface to which a load lock provided in the processing apparatus is connected, and a pair of side surfaces connecting the front surface and the rear surface in a device depth direction and facing each other in a device width direction, and a plurality of columns connected to the wall. Among the plurality of columns, a column disposed on a side of the rear surface is configured as an upper member and a lower member. An end surface of the lower member on the side of the rear surface in the device depth direction is disposed closer to the front surface than an end face of the upper member on the side of the rear surface in the device depth direction.

(Fig. 4)